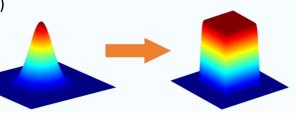




Beam Shaping

Beam Shaping Elements are diffractive optical elements (DOE) used to transform a nearly-Gaussian laser beam profile into a unique well-defined 2D shaped uniform intensity distribution and sharp edges in a specific work plane.



FEATURES

Flat-Top output intensity profile
Any desired shape including round, square, line, rectangle or custom
High efficiency
High-power threshold
Wavelengths from UV to IR
Optional AR/AR coating

APPLICATIONS

Material Processing applications:

Laser cutting

Laser Scribing

Laser Ablation

Illumination:

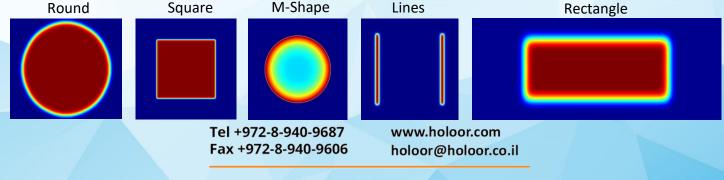
Wafer inspection

Lithography

DOEs can generate unique optical functions that are not possible by conventional reflective or refractive optical elements, providing greater flexibility in system configuration. Among the few advantages are: small footprint, fast/high throughput thanks to simultaneous processing, tailored energy distribution, etc. The operational principle is quite straightforward; from a collimated input beam, the output beams exit the DOE with a predesigned spot size and shape at a specific distance. Several examples are presented in Fig.1.

Beam Shaping a Gaussian beam into a flat profile provides higher quality of the process and enables more flexibility in the system configuration. For example, it allows system designers to increase laser pulse energy without increasing the processed spot area or line width.

Figure 1 Examples of Top-Hat Beam Shaping DOEs at the focal plane.







F-Theta

Lens

Top Hat

USE IN SCANNERS

- 1. To use a flat top beam shaper in a scanning setup, the optical designer needs to pay attention the following points:
 - 1.1. Use a collimated laser beam with DOE.
 - 1.2. Place the DOE before the scanning head
 - 1.3. Use a scanner lens (i.e. F-Theta lens) in order to achieve a well-focused spot at a certain distance, for all scanning angles, as shown in Fig.2.
 - 1.4. Make sure Scanner and F-theta aperture are at least2.2 times beam diameter.
 - 1.5. Make sure the F-theta gives diffraction limited performance over the entire scan range.
- 2. Energy distribution can be any non-uniform distribution required by the application.



Fused Silica, ZnSe
193 nm to 10.6 um
Large range of full angles
2-level (binary) to 16-level
86% - 96%
Few mm to 100 mm
AR/AR coating
Almost any size and intensity profile

